

The schematic diagram illustrates a power supply system for a plasma processing apparatus. A main power source, represented by a rectangular box labeled 3, is connected to a network of components. The system includes a series of resistors (11, 16) and inductors (14, 15). Five power supplies, labeled P1, P2, P3, P4, and P5, are connected to the network. The power supply P1 is connected to a central inductor (8) via a line 10. The inductor (8) is connected to a central point 9, which is further connected to a line 17. The inductor (8) is also connected to a central point 18, which is further connected to a line 19. The power supply P2 is connected to a central point 12, which is further connected to a line 14. The power supply P3 is connected to a central point 13, which is further connected to a line 15. The power supply P4 is connected to a central point 14, which is further connected to a line 15. The power supply P5 is connected to a central point 15, which is further connected to a line 14. The entire system is enclosed within a dashed line boundary.

Fig. 2

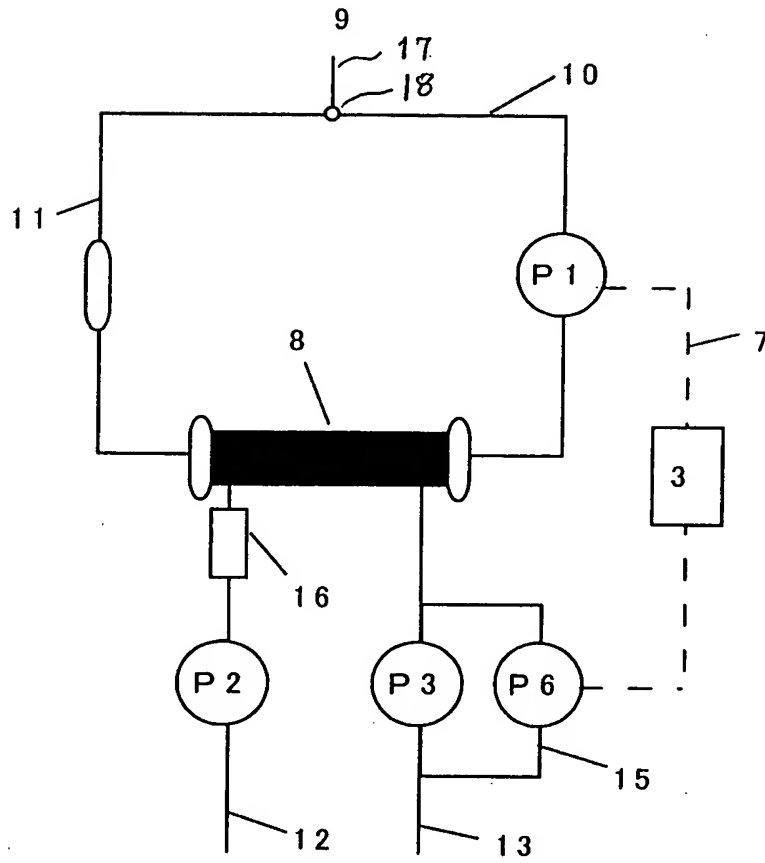


Fig. 3

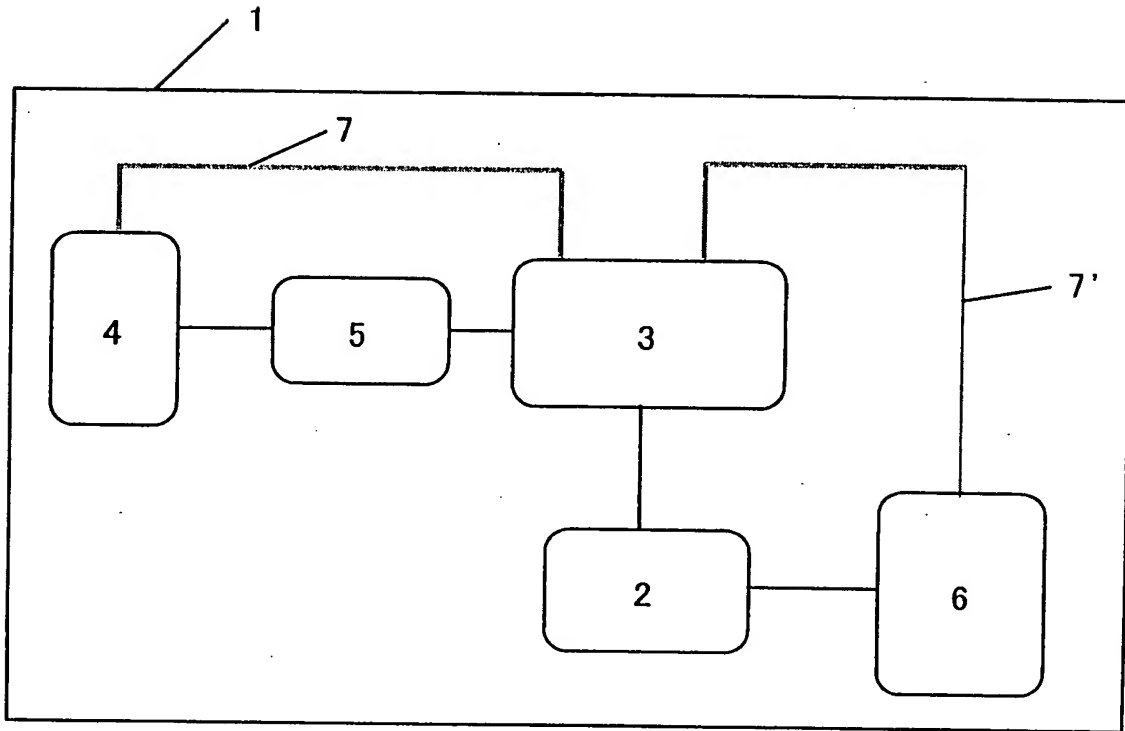


Fig. 4

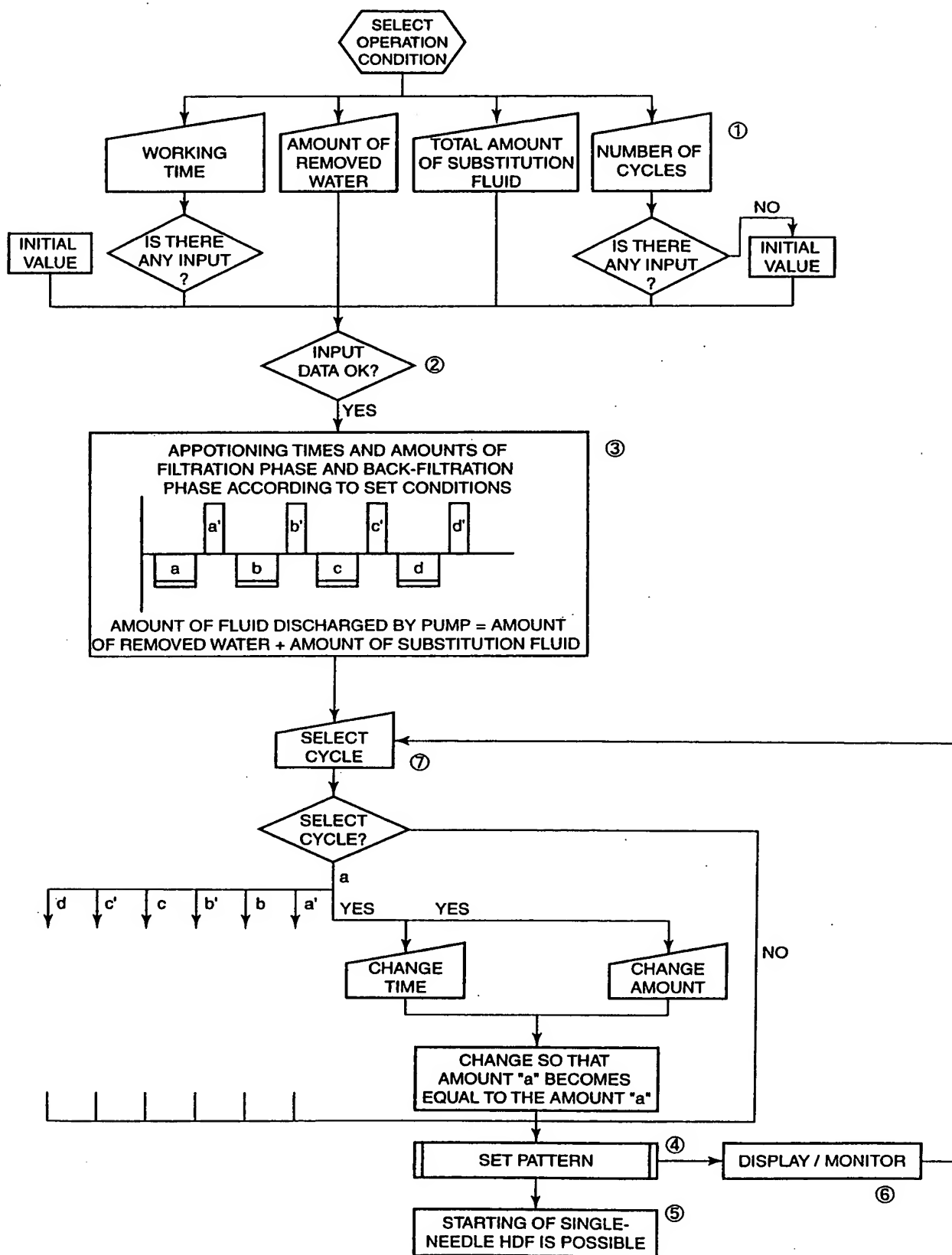


Fig. 5

